JUN 2 5 2003 35

219.40232X00

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

Sarah KIM et al.

Serial No.:

10/077,967

Filed:

February 20, 2002

For:

A PROCESS OF VERTICALLY STACKING MULTIPLE

WAFERS SUPPORTING DIFFERENT ACTIVE INTEGRATED

CIRCUIT (IC) DEVICES

Art Unit:

2822

Examiner:

Michael M. Trinh

## RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 June 25, 2003

Sir:

In response to the Restriction Requirement (Paper No. 5) dated on June 18, 2003, Applicants hereby elect, without traverse, Group II (claims 1-18).

## **REMARKS**

Claims 1-32 are pending in this application.

In response to the restriction requirement (Paper No. 5), in which the Examiner indicates that two groups of inventions are being claimed; namely Group I (claims 19-32) drawn to a 3-D vertical stacked wafer system, allegedly classified in class 257, subclass 773 and Group II (claims 1-18) drawn to a method of forming a vertical stacking wafers, allegedly classified in class 438, subclass 107, Applicants respectfully elect, without traverse, the invention of Group II directed to claims 1-18. Non-elected

Group I, drawn to claims 19-32, will be reinstated in a divisional application in due course.

To the extent necessary, applicants petition for an extension of time under 37 C.F.R. §1.136. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 of Antonelli, Terry, Stout & Kraus, LLP (referencing Attorney Docket No. 219.40232X00), and please credit any overpayment of fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

Hung H. Bu

Reg. No. 40,415

(703) 312-6600 HHB

1